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Mechanical Engineering Department, UMCP

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Integrated Measurement Technique for **Curing Process-dependent Mechanical Properties of Polymeric Materials Using** Fiber Bragg Grating



#### **Problem Definition**

- One of the most critical reasons to make modeling predictions uncertain is the non-linear and time-dependent mechanical behavior of the materials used in electronic packaging, especially polymeric materials for adhesive and underfill.
- · More and more polymeric materials are introduced everyday, but less and less time to evaluate them; very limited material property data are available for new polymeric materials.

#### **Research and Development Goals**

To develop an integrated measurement technique using a Fiber Bragg grating sensor to measure the processing and curing conditions dependent polymer properties rapidly but accurately.

- Chemical shrinkage
- Glass transition temperature
- Temperature-dependent coefficients of thermal expansion
- Temperature and time-dependent elastic modulus (visco-elastic constitutive behavior)

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# **Background: Fiber Bragg Grating**

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- Fiber Bragg grating (FBG) is a periodic perturbation of the refractive index along the fiber length.
- · A narrow band of the incident optical field within the fiber is reflected by successive coherent scattering from the index-varying bands.



Bragg resonance called Bragg wavelength







## **Basic Concept of Proposed Method and Experimental Setup**

• A polymer of interest is cured around a glass FBG and the BW shift will be documented while:

(1) Polymerization progresses at the curing temperature, (2) The temperature of the cured polymer changes.

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### Basic Concept of Proposed Method and Experimental Setup





#### **Specimen Configurations**

• Configuration I :  $r_3 > 200 r_1$  $E_{a} = 0.18 \, Gpa$ Core and C  $-\alpha_a = 10 \text{ ppm/}^{\circ}\text{C}$ • - α<sub>s</sub>=50ppm/<sup>0</sup>C (m 1.5 ' For  $r_1 \approx \infty$ ,  $\varepsilon_z = \varepsilon_f^\sigma = \alpha_s T_s - \alpha_f T_f$ Region for constant  $\Delta \lambda_{R}^{d}$  $\Delta \lambda_{R}^{d} = \lambda_{R} (1 - P_{k}) \varepsilon_{f}^{\sigma}$ . . . . . . . . . . . . . . . . . . E (GPa) For chemical shrinkage, For CTE,  $[0, 0 \le r < r_1]$  $T(r) = \Delta T, \ 0 \le r < r_3$  $T(r) = \begin{cases} 0 , r_1 \le r < r_2 & \implies \varepsilon_f^{\sigma} = \alpha_s T_s \end{cases}$  $\implies \varepsilon_f^{\sigma} = (\alpha_s - \alpha_f) \Delta T$  $T_s$ ,  $r_2 < r \leq r_3$  $\alpha_s = \frac{\varepsilon_f^{\sigma}}{\Delta T} + \alpha_f = \frac{\Delta \lambda_B^d}{\lambda_B (1 - P_k) \Delta T}$ Mechanical Engineering Department, UMCP Laboratory for Optomechanics and Micro/nano Semiconductor/Photonics Systems Copyright © 2011 LOMSS

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# Specimen Configurations





 $\Delta \lambda_a^a$  is extremely sensitive to  $E_s$ . And the unknown  $E_s$  can be determined from  $\Delta \lambda_a^a$  by solving the analytical solution numerically.



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# Implementation of the Proposed Method and Experimental Results



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